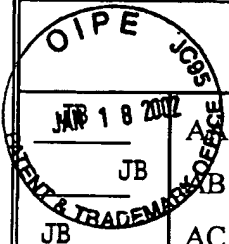


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	Applicant: Mamoru NAKASUJI et al.	
	Filing Date: June 27, 2001	Group Art Unit:

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	Applicant: Mamoru NAKASUJI et al.	
	Filing Date: June 27, 2001	Group Art Unit:

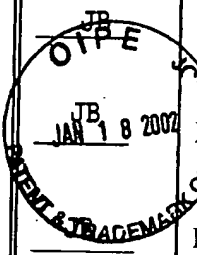
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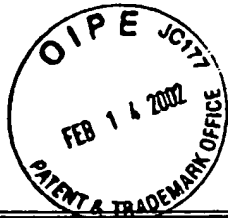
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JB	AV	Nakasuji	10/03/00			11/12/96
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<u>JB</u>	BI ✓	<i>High -Emittance and Low-Brightness Electron Gun for Reducing-Image Projection System: Computer Simulation</i> , Mamoru Nakasuji et al., Jpn. J. Appl. Phys. Vol. 36 (1997) pp.2404-2408.	
<u>JB</u>	BJ ✓	H. Hayashi, et al., <i>LSI Testing Symposium 1998, Minutes of the meeting</i> , P160 (1998) (partial translation)	
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<div style="text-align: center;">  JB ----- </div>	BK ✓	<i>Multi-Beam Concepts for Nanometer Devices</i> , B. Lischke et al., Japanese Journal of Applied Physics, Vol. 28, No.10, October 1989, pp. 2058-2064.
	BL ✓	<i>An electron-beam inspecting system for x-ray mask production</i> , P. Sandland et al., J. Vac. Sci. Technol. B9 (6), Nov/Dec. 1991, American Vacuum Society, pp.3005-3009.
	BM ✓	<i>Requirements and performance of an electron-beam column designed for x-ray mask inspection</i> , W.D. Meisburger et al., J. Vac. Sci. Technol. B9 (6), Nov/Dec 1991, American Vacuum Society, pp.3010-3014.
	BN ✓	<i>Table 5-1 Work Function in Metals</i> page 116.
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	Applicant(s): Mamoru NAKASUJI et al.	
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<u>JB</u>	AF 2000-100369 ✓	4/7/00	Japan	Yes/Abstract
<u>JB</u>	AG 2000-003692 ✓	1/7/00	Japan	Yes/Abstract
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<u>JB</u>	AK 11-233062 ✓	8/27/99	Japan	Yes/Abstract
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